

<b>APPLICATION DATA SHEET</b>
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Electronic Version v14

Stylesheet Version v14.0

<b>Title of Invention</b>	METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD
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Application Type: regular, utility

Attorney Docket Number: 36280

Correspondence address:

Customer Number:

000116

\*000116\*

Priority Data:

Doc.No: 2002-336415; Country - JP; Date: 2002-11-20 us-priority-claimed

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